

# CATRENE

## Programme Review

### Report 9

Cluster for Application  
and Technology  
Research in Europe  
on NanoElectronics

**Full year report**  
January - December 2014



# CATRENE Programme Review Year 2014

## Distribution list

- CATRENE Board
- CATRENE Support Group
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- CATRENE Steering Group Technologies
- CATRENE Director's Committee
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# Executive Summary

## EXECUTIVE SUMMARY

CATRENE (Cluster for Application and Technology Research in Europe on Nano-Electronics) is a EUREKA cluster programme dedicated to cooperative research in micro and nanoelectronics.

The CATRENE cluster programme (Σ! 4140) was approved by the EUREKA conference in Maribor on 25 October 2007, officially announced at the Ministerial Conference in Ljubljana on 06 June 2008, and started 01 January 2008 as a four year programme until year-end 2011. It has been extended until the end of 2015.

The following European Member States actively support CATRENE: Austria, Belgium, France, Finland, Germany, Ireland, Israel, Spain, Sweden, The Netherlands and Turkey.

The 2014 CATRENE Programme Review will cover the progress and actions undertaken throughout the year to meet the programme's objective, which is to foster technological Leadership for a competitive European ICT.

Chapter 1 provides an overview of the CATRENE programme while chapter 2 and 3 focus more specifically on 2014 projects and actions.

### Overview of CATRENE

The CATRENE programme opened its 1st Call for Project Proposals on 29 February 2008. Today, a total of 7 calls have been launched resulting in 66 labelled projects and a total effort of 8 829 PYs.

At the end of 2014, 23 CATRENE projects had successfully ended.

### Results of CATRENE Call 7 and launch of CATRENE Call 8

In 2014, CATRENE launched its 7th Call for Project Proposals. Altogether, 7 projects were labelled amounting to 799 PYs.

It is of interest to note that SAM3 and SIPOB-3D have been co-labelled by CATRENE and EURIPIDES<sup>2</sup>.

### European Nanoelectronics Forum 2014

The seventh edition of the European Nanoelectronics Forum took place in Cannes, France, on 26-27 November 2014 under the theme *Enabling Smart Solutions*.

Jointly organized by AENEAS, the EUREKA Cluster CATRENE, the ECSEL Joint Undertaking and the European Commission, the event had a good participation of 270 attendees from all over Europe.

During the forum, the project EM4EM received the CATRENE Innovation Award for its outstanding results which are pre-conditions for the next generation of electric vehicles, allowing European companies in the automotive industry to secure and expand while preserving or even increasing employment in Europe.

The feedback received in the questionnaire sent to participants at the end of the event showed a very high level of satisfaction, in particular with regards to the setup of the Project Village and

to the richness of the programme.

In addition to the day to day activities in 2014, reflection on a new tool for beyond 2015 was addressed. Industry proposed to start a new EUREKA cluster for micro and nanoelectronics. A dedicated Joint Working Group between National Authorities and Industry, which had the mandate to develop a concept for a new cluster, formulated new ideas for the scope and the organisation - based on the recommendations in the assessment report and the feedback received through interviews with the European Electronic Components and Systems community. A first draft was presented and discussed at the common meeting between National Authorities and Industry in April 2014.

At the same time, the new ECSEL Joint Undertaking was started by the European Commission and the Member States, focusing on the value chain from micro and nanoelectronics until System Integration. The requirement of the Public Authorities was to show that the planned new EUREKA Cluster and ECSEL are complementary tools - while having overlaps in content. During the year 2014, a lot of effort was put into the preparation of the concept for the New Tool. The concept was presented to the Public Authorities in November 2014. A detailed reaction with "cornerstones" for the New Tool is expected early 2015. The final decision on the establishment of a New EUREKA Cluster for micro and Nanoelectronics will most probably be taken in March 2015.



# Overview of CATRENE

## 1. Overview of CATRENE

The CATRENE programme opened its 1st Call for Project Proposals on 29 February 2008. Today, a total of 7 calls have been launched resulting in 66 labelled projects. By the end of 2014, 23 CATRENE projects had successfully ended.

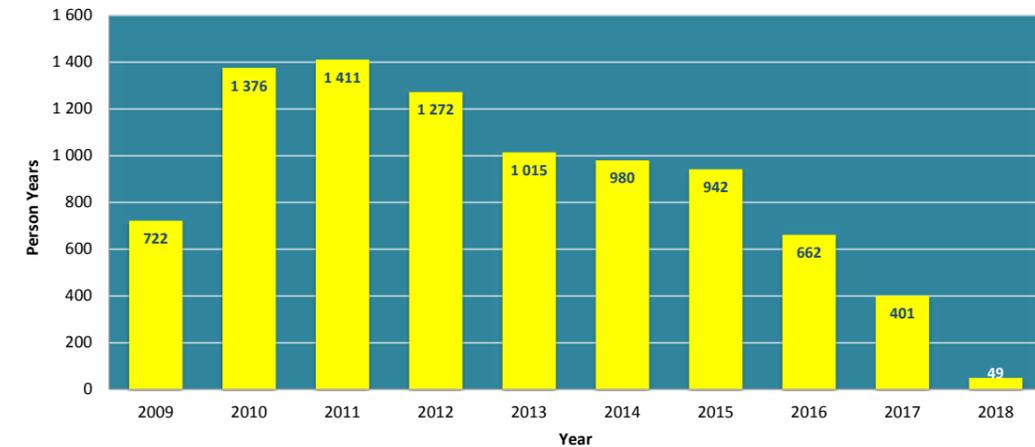
Call	PO received	FP received	Labelled	Out of the labelled are:		
				Cancelled /merged/ transferred/ suspended	Successfully Ended	Active
<b>1<sup>st</sup> Call</b>	<b>18</b>	<b>15</b>	<b>14</b>	<b>5</b>	<b>9</b>	<b>0</b>
Applications	10	8	8	3	5	0
Technologies	8	7	6	2	4	0
<b>2<sup>nd</sup> Call</b>	<b>14</b>	<b>10</b>	<b>10</b>	<b>3</b>	<b>7</b>	<b>0</b>
Applications	9	7	7	3	4	0
Technologies	5	3	3	0	3	0
<b>3<sup>rd</sup> Call</b>	<b>15</b>	<b>10</b>	<b>10</b>	<b>3</b>	<b>6</b>	<b>1</b>
Applications	7	4	4	2	2	0
Technologies	8	6	6	1	4	1
<b>4<sup>th</sup> Call</b>	<b>19</b>	<b>14</b>	<b>10</b>	<b>1</b>	<b>1</b>	<b>8</b>
Applications	10	8	7	1	0	6
Technologies	9	6	3	0	1	2
<b>5<sup>th</sup> Call</b>	<b>8</b>	<b>5</b>	<b>5</b>	<b>1</b>	<b>0</b>	<b>4</b>
Applications	5	3	3	0	0	3
Technologies	3	2	2	1	0	1
<b>6<sup>th</sup> Call</b>	<b>13</b>	<b>10</b>	<b>9</b>	<b>2</b>	<b>0</b>	<b>7</b>
Applications	9	7	6	1	0	5
Technologies	4	3	3	1	0	2
<b>7<sup>th</sup> Call</b>	<b>9</b>	<b>9</b>	<b>8</b>	<b>1</b>	<b>0</b>	<b>7</b>
Applications	5	5	4	1	0	3
Technologies	4	4	4	0	0	4
<b>Per end of 2014</b>	<b>96</b>	<b>73</b>	<b>66</b>	<b>16</b>	<b>23</b>	<b>27</b>

Over the course of the entire CATRENE programme, a total of 16 projects were cancelled/merged due to national eligibility criteria, funding constraints and in some countries even as a result of reduced funding volume. In 2014, two projects (1 from Applications and 1 from Technologies) labelled during the 6th Call were cancelled due to funding issues.

Resources, participants and work areas

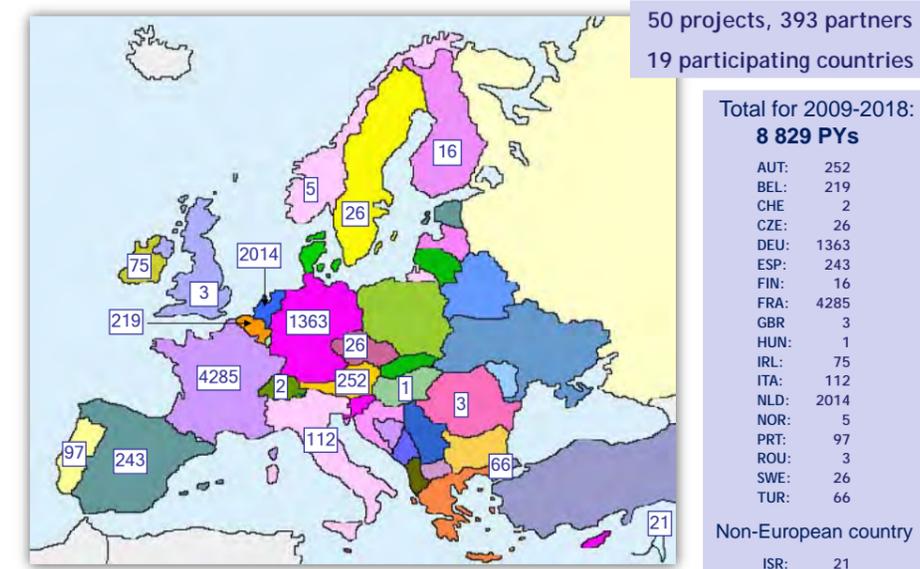
The following graphs provide an overview of the CATRENE project resources (in PYs), of their participants and of their related work area.

**CATRENE Calls 1 to 7 labelled resources**  
Total PYs: 8829\*

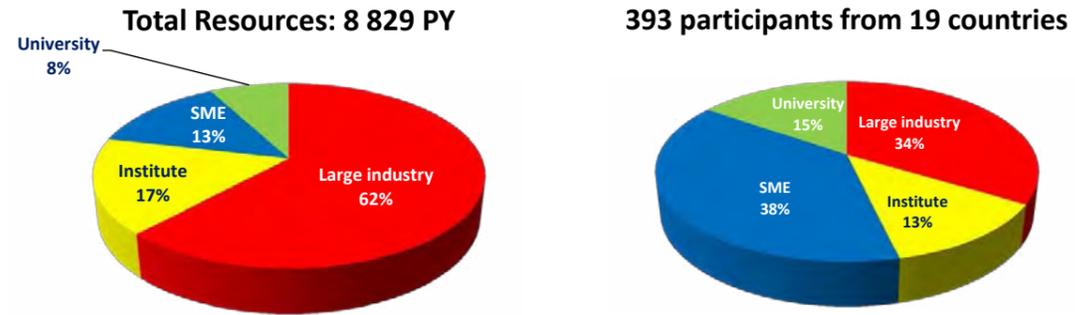


\*This figure does not include the person years of MEDEA+ projects which continued running until 2010.

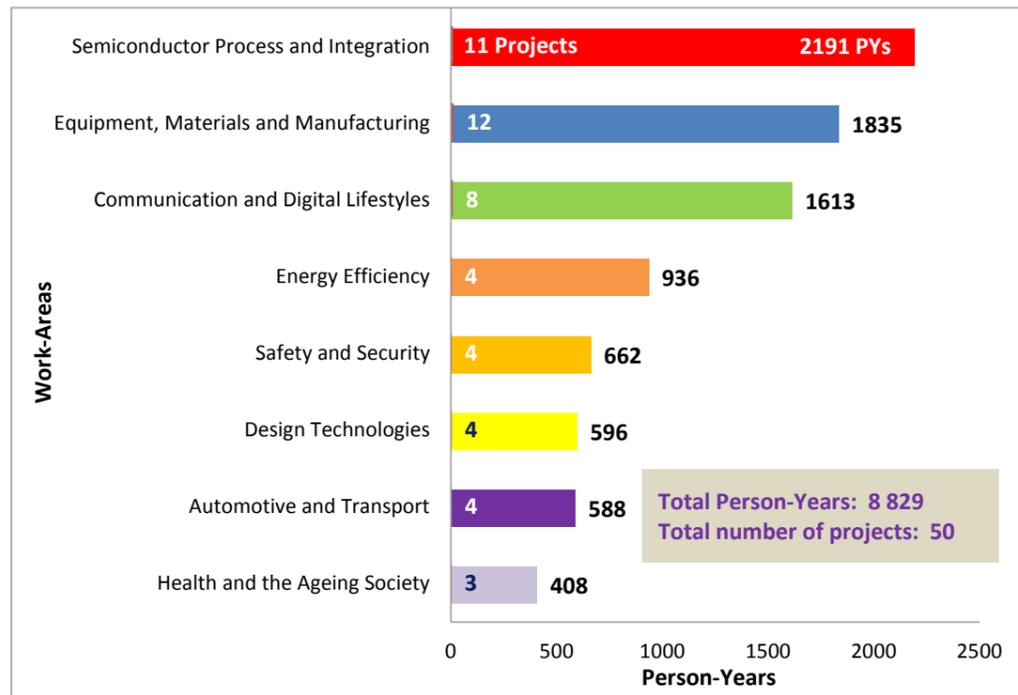
**CATRENE resources per country as per year end 2014**



### Structure of CATRENE projects



### CATRENE labelled projects - split by work area



For a more detailed list of projects according to work areas, see Appendix B. CATRENE projects focus matrix at the end of this document.

# CATRENE Year in Review

## 2. 2014 CATRENE Year in Review

### 2.1. Achievements

#### 2.1.1. Reflection on a new tool for beyond 2015

Industry proposed to start a new EUREKA cluster for micro- and nanoelectronics. A dedicated Joint Working Group between National Authorities and Industry, which had the mandate to develop a concept for a new cluster, formulated new ideas for the scope and the organisation - based on the recommendations in the assessment report and the feedback received through interviews with the European Electronic Components and Systems community. A first draft was presented and discussed at the common meeting between National Authorities and Industry in April 2014.

At the same time, the new ECSEL Joint Undertaking was started by the European Commission and the Member States, focusing on the value chain from micro- and nanoelectronics until System Integration. The requirement of the Public Authorities was to show that the planned new EUREKA Cluster and ECSEL are complementary tools - while having overlaps in content. During the year 2014, a lot of effort was put into the preparation of the concept for the New Tool. The concept was presented to the Public Authorities in November 2014. A detailed reaction with “cornerstones” for the New Tool is expected early 2015. The final decision on the establishment of a New EUREKA Cluster for micro and Nanoelectronics will most probably be taken in March 2015.

#### 2.1.2. Call 7

In 2014, CATRENE launched its 7th Call for Project Proposals. The call opened with a Brokerage Event on 05-06 February in Brussels, attended by more than 200 people from across Europe. During the event, more than 40 project ideas for CATRENE and the ENIAC JU were identified and elaborated on.

CATRENE 7 <sup>th</sup> Call 2014		
Call opens	04 February	Labelling sessions: 22 October 25 November
PO submission ends	05 April	
Communication on selected POs	25 May	
FP submission opens	01 June	
FP submission ends	04 September	
<b>Projects start 01 January 2015</b>		
<i>Participation in Project Outline (PO) phase is <u>mandatory</u> for participation in subsequent Full Proposal (FP).</i>		

Altogether, 7 projects were labelled by CATRENE as a result of CALL 7 amounting to 799 PYs.

Call #	Project Number	Acronym	Work Area	PYs
7	CAT120	CISTERN	Communication & Digital Lifestyles	116
7	CAT121	EAST	Communication & Digital Lifestyles	193
7	CAT209	H2O	Safety and Security	206
7	CAT406	NEMADE	Health and the Ageing Society	15
7	CAT601	SIPOB-3D	Design Technology	102
7	CAT801	TSV-HANDY	Equipment, Materials and Manufacturing	50
7	CAT802	SAM3	Equipment, Materials and Manufacturing	117

It is of interest to note that SAM3 and SIPOB-3D have been co-labelled by CATRENE and EURIPIDES<sup>2</sup>.

More details on the projects labelled in Call 7 are available in Chapter 3 of this publication.

#### 2.1.3. Increased links and cooperation with other Clusters/Programmes

The mission of CATRENE is to promote and to strengthen the European nanoelectronics R&D&I community. CATRENE and other EUREKA Clusters have been recognised as the only initiatives directly managed by R&D&I actors in regular contact with the EUREKA network and Public Authorities.

According to its mission, CATRENE is cooperating with other initiatives and organisations supporting the nanoelectronics domain:

- CATRENE and its predecessor programmes exists since 1987 and has continuously collaborated with the other EUREKA Clusters.
- CATRENE has co-labelled projects with other EUREKA Clusters and European funding programmes.
- An Inter-Cluster Committee has been created in 2010 to reinforce this cooperation.
- CATRENE has a strong link with the industry association “AENEAS” representing R&D&I actors in the ECSEL JU.
- CATRENE and AENEAS work together to define a common ‘Vision, Mission and Strategy’ (VMS) - the reference document for projects in CATRENE, ENIAC JU and the ECSEL JU.
- CATRENE and AENEAS host a Common Brokerage Event each year to prepare upcoming CATRENE and ECSEL calls.
- CATRENE organises the annual European Nanoelectronics Forum with the contribution of

the AENEAS, ECSEL JU and DGConnect (FP7) where projects and speakers from the three programmes are presented.

## 2.2. Events

A number of events underlined the CATRENE communication strategy in 2014, reaching from the very technically oriented and network focused Brokerage Event for experts to the yearly European Nanoelectronics Forum, which has achieved a high level of recognition in Europe today.

### 2.2.1. European Nanoelectronics Forum 2014 and CATRENE Innovation Award

The European Nanoelectronics Forum 2014 took place in Cannes, France on 27-28 November. 270 participants from all over Europe attended the event organised under the theme *Enabling Smart Solutions*. During the plenary session, the audience showed high appreciation for the speeches delivered, notably by Ben Verwaayen (Chairperson of the ELG), Philip Moynagh (Intel) and Berthold Hellenthal (Audi). The Project Village was organised in an area of 850 m<sup>2</sup> and presented 70 projects from CATRENE, the ENIAC JU and the European Commission's FP7 programme. The new setup of the village, compared to previous years, was optimised to favour discussion and networking. A total of 4 Speakers' Sessions were organised in the exhibition area during which hot topics were presented in an informal setting. The high number of participants in the sessions was unforeseen (15 participants per session in 2013 compared to +/-80 in 2014) and as a consequence the set up was not optimal. This will be corrected for 2015.



The feedback received in the questionnaire sent to participants at the end of the event showed a high level of satisfaction and that expectations were met at 95%.

The event was jointly organised by AENEAS, CATRENE, the ECSEL Joint Undertaking and the European Commission.

During the event, the project EM4EM (ElectroMagnetic reliability of electronic Systems for Electro Mobility) was chosen 2014 winner of the CATRENE Innovation Award. The results of the project are pre-conditions for the next generation of electric vehicles, allowing European companies in the automotive industry to secure and expand while preserving or even increasing employment in Europe.



The objective of the EM4EM consortium is to cut out this interference as much as possible while extending its impact to the development of electronics that are better able to withstand electromagnetic interference. With a strong interdisciplinary consortium led by Audi and including automotive manufacturers, suppliers, semi-conductor manufacturers from three European countries, as well as universities, the EM4EM project has already produced impressive results. EM4EM deliverables (including tried and tested models, measurement methods and procedures as well

as simulation tools) will benefit a large number of European businesses by reducing time-to-market and costs of EMR-optimised components and systems for electric vehicles. The demonstrators along the value chain, for example, will help third parties integrate these results quickly into new products.

The CATRENE Innovation Award is bestowed each year to a project with a high level of innovation and far-reaching exploitation potential, market impact and overall benefits for Europe, as well as, creative objectives and effective management.

The next European Nanoelectronics Forum will be held on 01-02 December 2015.

### 2.2.2. Common AENEAS and CATRENE Brokerage Event 2014

The AENEAS/CATRENE Common Brokerage Event 2014 took place in Brussels, Belgium on 05-06 February and was held back-to-back with the ARTEMIS-IA Brokerage Event. Every year, the event brings together the European Nanoelectronics Community, to generate ideas for project proposal for the next CATRENE and ECSEL calls and to start consortia preparations.

The programme of the event is based on sessions covering the work areas common to both the CATRENE White Book and the ECSEL JU MASP:

- Communication and Digital Lifestyles
- Automotive and Transport
- Energy Efficiency
- Safety and Security
- Health and the Ageing Society
- Design Technologies
- Equipment, Materials and Manufacturing
- Semiconductor Process and Integration

During each session, a designated leader moderates the discussion around new project ideas along with consortia building.

During the 2014 edition, more than 230 participants worked together over the 2 days of the event coming up with more than 40 preliminary project ideas.

### 2.2.3. CATRENE Scientific Committee Workshop

*"Smart Systems for Healthcare and Wellness"*

See 2.3.2

## 2.2.4. CATRENE Design Technology Conference 2014

The CATRENE Design Technology Conference was held in June 2014 in Grenoble. It was carried out in conjunction with the Leti Days Conference.

73 Delegates belonging to 30 different organisations and coming from 6 European countries (Austria, Finland, France, Germany, The Netherland, and Spain) attended the conference. The mix of representatives from industry and academic creates ideal opportunities for a professional exchange of ideas on a scientific basis.

The focus of the event was on application-oriented design methods for micro- and nanoelectronic products.

Based on this, DTC was organised into 5 Technical Sessions:

1. Reliability of SoCs in Safety Critical Applications
2. Power and thermal aware design
3. Energy efficient HPC
4. Power Electronics
5. Design enablement for advanced silicon technologies

and 2 Panels:

- What are the next growth areas in multimedia beyond TV, mobiles phones/tablets, STB,...?
- EDA beyond IC design

Held annually, the CATRENE DTC has become the meeting point for Europe's scientists and experts in applications-oriented design. It is a unique opportunity to meet the CATRENE projects researchers while enjoying the high quality program of the conference. However, attendees all agree that the best thing about DTC is the technical results which are presented by real experts from the field. The confluence of academic and industrial perspectives as well as electronic system design and manufacturing perspectives is unlike any other conference.



## 2.3. Publications

### 2.3.1. Project Profiles and Result Sheets

As of the end of 2014, 34 CATRENE Project Profiles and 16 CATRENE Result Sheets have been produced and published on the web.



### 2.3.2. Scientific Committee Report on Smart Systems for Health and Wellness

The CATRENE Scientific Committee released the 'Smart Systems for Health and Wellness' report in February 2014 during a workshop in Brussels that gathered close to 80 participants.

The report and workshop focused on the key role that micro- and nanotechnology can play in finding solutions for this problem. Over the last 60 years, semiconductor technology has progressed tremendously. Following Moore's law, huge computation power has become available into handheld devices, sensors have shrunk in size, and wireless communication has penetrated into the consumer market, to name only a few developments. The next step is the migration into wearable devices. Already many products are appearing on the market, but with limited functionality and unfit for long term continuous monitoring. More research is needed to obtain that goal. This report will focus on the technology challenges that still lie ahead, and discuss possible solutions.

Various technologies are reviewed in the report with the following keywords in mind: prevention (including the promotion of healthy lifestyle through fitness and stress monitoring), diagnostic, therapy and therapy monitoring as well as decentralization from hospital to home maintenance. Three large applications are targeted: Devices for the healthy, devices to cure, and devices to aid the chronically ill ("stay fit", "get well", "a better live"). They have to operate unobtrusive, need full autonomy and are either wearable or implantable. Small devices (cm to mm size), with a typical power budget between several  $\mu$ W and a few mW are envisaged.



The report received a high level of support from Industry and is available for download on the CATRENE website.

## 2.4. Press Coverage

The overview of 2014 press coverage is available on the CATRENE website in the communication section under Press Clips, and includes a link to view the complete text.

Article	Source	Country	Year 2014
5 milliards d'euros pour la R&D européenne en nanoélectronique et systèmes embarqués d'ici 2020	ElectroniqueS	FRA	January
Avec Ecsel, l'Europe devra passer du développement à la commercialisation de produits	ElectroniqueS	FRA	January
edaWorkshop und CATRENE DTC 2013 - Ein Rückblick	edacentrum	DEU	January
European Nanoelectronics Forum: Innovation for growth	edacentrum	DEU	January
A breakthrough in EUV technology	EUREKA News	BEL	February
Denis Rousset directeur du bureau Catrene, cluster Eureka dédié à la nanoélectronique	ElectroniqueS	FRA	24 March
Gérard Matheron (Acsiel): «Il faut assouplir les règles européennes sur les subventions publiques»	ElectroniqueS	FRA	21 May
Jean-Luc Maté devient président du comité Intercluster d'Eureka	ElectroniqueS	FRA	20 June
Le projet Thor ouvre des débouchés prometteurs pour les composants en carbure de silicium	ElectroniqueS	FRA	3 July

Article	Source	Country	Year 2014
10 new innovative nanoelectronics projects in EUREKA CATRENE's pipeline	EUREKA News	BEL	1 August
The Importance Of Kitchen Tables And Pubs	Electronics Weekly	GBR	26 November
EC IC Manufacturing Boost May Need Foreign Investment	Electronics Weekly	GBR	26 November
There's Still Hope	Electronics Weekly	GBR	26 November
EC will support foreign semi manufacturers if locals won't invest	Electronics Weekly	GBR	26 November
Ledproject met grote Nederlandse inbreng wint innovatieprijs Eniac	Bits&Chips	NLD	27 November
Die letzte Chance nutzen	elektroniknet	DEU	27 November
Der finanzielle Rahmen ist geschaffen	elektroniknet	DEU	27 November
IoT Gets Woolly In Cannes	Electronics Weekly	GBR	27 November
Increasing SME involvement in EC R&D programmes	Electronics Weekly	GBR	27 November
Europe Must Fund First Production Fabs, says Chery	Electronics Weekly	GBR	28 November
European Nanoelectronics Forum a real success for EUREKA nanoelectronics Cluster CATRENE	EUREKA News	BEL	18 December
Zuken Plays Key Role in Innovation Award Win for Electric Vehicle Research Collaboration	Zuken		19 December

<i>Article</i>	<i>Source</i>	<i>Country</i>	<i>Year 2014</i>
<i>Industry News</i>			
Précédent   L'Europe de l'industrie et du numérique à l'heure des choix politiques   Suivant Usine Digitale > Semi-conducteurs L'Europe ne fait rien pour soutenir la production dans les semi-conducteurs, s'indigne la profession	L'Usine Digitale	FRA	20 May

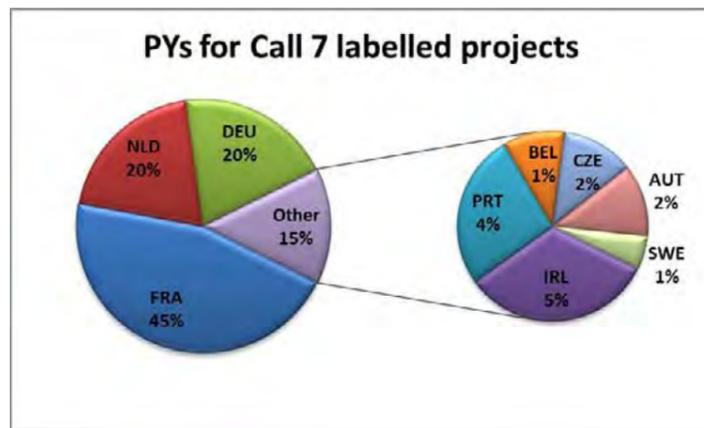
# Review of Call 7 & Projects Ended in 2014

### 3. Review of Call 7 and projects ended in 2014

A total of 9 Project Outlines leading to 9 Full Proposals were received in 2014. From these 9 proposals, 8 were labelled and one withdrew.

The Call 7 projects amount to a total effort of 799 Person Years. The countries contribution is dominated by France with 45% of the efforts followed by Germany and The Netherlands with respectively 20% of the total efforts as illustrated in the Figure 1 below.

Figure 1: Call 7 labelled projects - PYs per country



Concerning technologies, the projects are clearly orientated along the More than Moore axis, with as first topic of interest the 3D IC and 3D system in package. In particular, the Call 7 covers the problematics of design tools, wafer handling equipment and failure analysis instruments for these new generations of ICs (see Figure 2 for relationship between these projects and their respective domains). Always along the More than Moore axis, the Call addresses the challenge of RF function integration in RF front end SoC for the fifth generation of mobile network.

Regarding applications, security in the Internet of Things is a strong thematic addressed in this Call through the development of secure wearable objects. The development of new generations of CMOS image sensors for healthcare, security, entertainment and automotive is gathering the rest of the effort.

#### Ending projects

Over the course of 2014, 9 projects ended with a majority belonging to the third Call of CATRENE. It is important to note that 2014 has seen the end of all CATRENE projects focusing on 450nm.

### 3.1. Call 7 & unsolicited projects (labelled in 2014)

#### 3.1.1. Overview Table

Call #	Project Number	Acronym	Work Area	PYs
7	CAT120	CISTERN	Communication & Digital Lifestyles	116
7	CAT121	EAST	Communication & Digital Lifestyles	193
7	CAT209	H2O	Safety and Security	206
7	CAT406	NEMADE	Health and the Ageing Society	15
7	CAT601	SIPOB-3D	Design Technology	102
7	CAT801	TSV-HANDY	Equipment, Materials and Manufacturing	50
7	CAT802	SAM3	Equipment, Materials and Manufacturing	117

#### 3.1.2. Project CAT120 CISTERN

*Cmos Image Sensor Technologies' Readiness for Next generation of applications*

Project leader: Klaas Jan Damstra (Grass Valley)

#### Brief description:

The objective of CISTERN is to address societal needs in the areas of security, and entertainment. These societal needs include citizens' security through Ultra High Definition surveillance systems, intelligent security systems through 3D vision, image capture for the first generation of Ultra High Definition Television, and sorting in the food industry. CISTERN addresses these needs by improving the performance of advanced image capturing systems (imagers) such as time-of-flight cameras, high-resolution/high sensitive and hyper- and multi-

spectral security cameras, and broadcast cameras. Improved image quality allows for the extraction of more detailed information and a wider range of applicability.

In particular, the goal of the CISTERN project is:

- To develop CMOS imager sensors with improved performance on spatial resolution, temporal resolution, higher bit depths, lower noise, wider colour gamut, higher quantum efficiency (not necessarily all combined for each sensor) and additional, smart functionality in the pixels. The consortium will develop imager sensors in the categories UHDTV, Time-of-Flight and hyper- and multi-spectral, for the application areas broadcast, entertainment, and security.

- To develop real time image processing techniques needed to improve the quality of the digital output signal of the sensor demonstrators.
- To develop and demonstrate the capability to produce multispectral imagers by hybridization of multispectral filter arrays on top of CMOS sensor. Both matrix filters and hybrid assembly process will be developed within the project.
- To demonstrate the improved performance of the CMOS imagers combined with related processing in a number of demonstrators.
- To develop Ultra High resolution, widely opened, sensor adapted zoom lenses (2/3" format, 4K resolution) for broadcast and security applications/markets.
- To optimize lens design in term of performance/cost/weight/camera integration for integral imaging chains.
- To develop and demonstrate an integrated Camera Lens Assembly for security applications that offers UHDTV performance with Size and Weight of an HDTV solution.
- To start in-house CMOS image sensor development in Grass Valley.

This project will build strong links with the ECSEL JU project EXIST.

Countries: Belgium, France, The Netherlands

#### Partners:

Belgium	SoftKinetic Sensors
France	Le2i-University of Burgundy, SILIOS Technologies (sub-contractor of Le2i), Thales
The Netherlands	Adimec, Grass Valley, TU Delft

Expected start date: 01-04-2015

Expected end date: 31-03-2018

### 3.1.3. Project CAT121 EAST

*Smart Everything everywhere Access to content through Small cells Technologies*

Project leader: Philippe Meunier (NXP Semiconductors)

#### Brief description:

Today the wireless user is served by power-hungry 2G/3G/4G macro/micro-cell base stations still having bounds on their data capacity, while the available spectrum has become a scarce resource. Fifth-generation (5G) mobile networks based on more and low power cells are expected to overcome these limitations and truly enable smart, high-speed, everything everywhere access to their end users. In these low power networks, the technology for base station will have much more similarities to those of the handsets compared to the situation in 3G/4G applications.

However, to make the small cells network solution successful technically and commercially for 5G, the following requirements on the RF front ends part of the Base station and handset have to be fulfilled:

1. Drastic cost & size reduction through integration;
2. Reduced energy consumption;
3. Improved re-configurability, adaptability and MIMO functionality.

EAST responds to these constraints for 5G networks up to 6GHz, working on technologies, packaging, signal processing, architecture design, and modelling for both base stations and mobiles. This clear focus on the "low" GHz range addresses the general expectation that this market segment will represent the highest economic value with the lowest environmental (energy consumption) impact. In particular, to fulfil the first requirement endowing cost re-

duction and miniaturization, EAST will research on:

- The high-density integration capabilities of CMOS/BiCMOS silicon technologies for the integration of antenna switch, low noise amplifiers and medium noise amplifiers;
- New packaging technics handling at the same time low insertion losses and good thermal dissipation.

Concerning energy saving, EAST will propose solution in the field of:

- Signal processing algorithms, to decrease computational power in the digital pre-distortion process;
- Technologies, exploiting the much better power-handling capabilities of LDMOS.

For the last field of requirement EAST will work on:

- Design, with fully digital Tx solution, enabling easy reconfiguration;
- Architecture for antenna array, enabling the MIMO capability.

Countries: France, Ireland, The Netherlands, Portugal

#### Partners:

France	3DIS Technologies, AMCAD Engineering, Cassidian, CEA-LETI, Ethertronics, III-V LAB, IMS Laboratory-University of Bordeaux, Institut Mines-Telecom/Telecom Paris-Tech, NXP Semiconductors, Sequans Communications, Thales Communications & Security, XLIM Xlim
Ireland	Alcatel-Lucent

The Netherlands	Anteverta-mw, Besi, Bruco Integrated Circuits, Delft University of Technology, NXP Semiconductors, TNO, TUE - Technical University of Eindhoven
Portugal	GSLDA, Instituto de Telecomunicacoes, NANIUM

Expected start date: 01-04-2015

Expected end date: 31-03-2018

### 3.1.4. Project CAT209 H2O

*Human to Objects "Easy Interactions in the Smart City"*

Project leader: Christian Dietrich (Gemalto)

#### Brief description:

The purpose of the H2O project, capitalizing on former results from the CATRENE eGo project, is to develop the requested architecture to put the human in control of the smart objects surrounding, put on or in him, so as to develop a human centric and privacy ensuring security architecture to support the rapidly emerging Wearable computing and IoT markets. The project will investigate the human to object interactions in different application areas of the smart city domain: communication, transportation, e-health and e-retail. The purpose of this work will be to study and implement advanced architecture concepts and technology bricks felt as missing for the deployment of efficient wearable computing solutions, as resulting from the former successfully ended eGo project and also to develop new user experience for a complete adoption of this new digital lifestyle. The major assets delivered by the project will be:

- A high-performance, reliable, ultra-low-power BCC (Body Communication Coupling) technology with a standardized physical layer which should be usable as

communication enabler in any Body Area Network. The eGo project has demonstrated the need to improve the BCC interface for addressing harsh environments.

- A representative set of non-intrusive, secure, low-cost, always working, wearable devices, suitable for several application domains pertaining to the IoT or smart-city area (in particular, ehealth, communication, safety and security, and retail). The eGo project has prototyped some form factors acceptable by a large category of users, and the project intend to implement robust and easy-to-use form factors (e.g. bracelet, clips...) suitable for the target applications.
- A fully trusted and privacy preserving transaction environment, enabling the object(s) that the user wears or can touch to seamlessly initiate applications or communication with or between objects.
- An Open SDK and application certification tool-chains enabling third party developers to easily develop apps for wearable and guarantying that such app can be automatically verified before being remotely loaded in the wearable devices owned by the user.
- To complete reference and trusted security architecture enabling seamless secure synchronization of wearable devices. This synchronization includes the recovery of credentials into a blank wearable device.
- To pilot implementation of wearable computing scenarios in some IoT or Smart-City application domains, together with first QoS or QoE feedback reports.

Countries: Czech Republic, France, Ireland, Portugal

#### Partners:

Czech Republic	IMA - Institute of Microelectronic Applications
France	ASTUS, CEA-LETI, CEA LIST, Gemalto, IDATE, Insight SiP, Oberthur Technologies, SORIN CRM, STMicroelectronics, Trusted Labs, Worldline
Ireland	Electro Automation, InHandGuides, Institute of Technology Cork, Tyndall National Institute
Portugal	GSLDA, Instituto de Telecomunicacoes

Expected start date: 01-12-2014

Expected end date: 30-11-2017

#### 3.1.5. Project CAT406 NEMADE

##### *New Mammography Detector*

Project leader: Jan T. Bosiers (Teledyne DALSA)

##### Brief description:

This project aims at developing a new generation, multi-modality (screening, biopsy and tomosynthesis) mammography detector, bringing better imaging performance at lower X-ray dose and higher patient comfort, at a lower cost. The incumbent technology is at a point where it can no longer meet new application and regulatory requirements like higher speeds, multi-modality and lower patient X-ray dose. The improved sensitivity and precision of the new generation detectors will also enable improved treatment. As benchmark, the current detectors for mammography are considered. Access to clinical validation is secured via SigmaScreening through co-founder Prof. Dr. Den Heeten who works at the Department of Radiology of in the Academic Medical Center (AMC) in Amsterdam, or by clinical trials by a selected OEM.

The five main technical goals are:

1. More efficient X-ray energy conversion and improved image contrast by improved scintillator performance;
2. Detector using newest generation CMOS imagers allowing additional features like switchable saturation dose, dual-energy compatibility and real-time X-ray dose sensing and control; and improved imaging processing capabilities;
3. Improved assembly technology matching the stringent requirements for high-resolution mammography applications, combined with high reliability;
4. More personalized mammography and higher patient safety by adaptive breast compression, reduced X-ray dose and shorter imaging cycles, fewer re-takes, fewer incorrect screening diagnosis results;
5. Lower cost: lower cost for detector and ownership, more efficient diagnosis and treatment.

Countries: The Netherlands, Sweden

#### Partners:

The Netherlands	SigmaScreening, Teledyne DALSA
Sweden	Scint-X

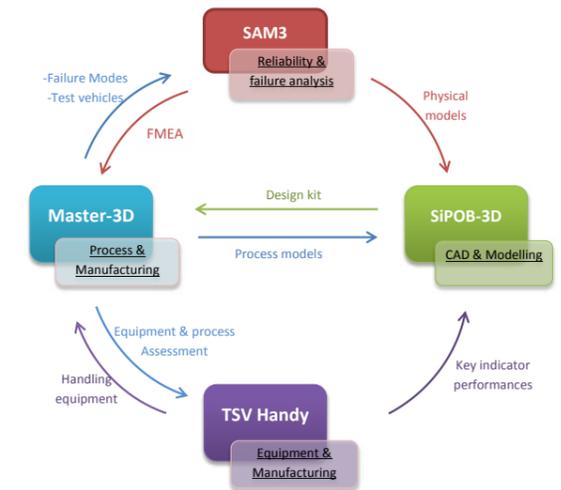
Expected start date: 01-01 2015

Expected end date: 31-12-2017

#### CATRENE Call 7 technology focus: 3D-ICS Projects

The three following projects of the 7th Call belong to the same topics: "3D-ICS". Figure 2 illustrates their respective area and the relationship between them. The on-going project Master-3D has been added to emphasise the coherence of the CATRENE projects related to 3D-ICS.

Figure 2: Links between CATRENE on-going and forthcoming 7th Call projects related to 3D-ICS



#### 3.1.6. Project CAT601 SiPoB-3D

*Co-Design for System-in-Package-on-Board: Managing Complexity and Diversity to Create Novel 3DCompact Systems*

Project leader: Klaus Pressel (Infineon Technologies)

##### Brief description:

More than Moore (MtM) technologies, three-dimensional (3D) high density technologies, and System-in-Package (SiP) technologies are prerequisites for compact system integration, which is needed for smart city applications. These compact systems require a mix of many new interconnect technologies such as through silicon via (TSV), through encapsulant via (TEV), redistribution layers (RDL), or micro-bumps, as well as encapsulation technologies, substrates, leadframes and a mix of many different materials.

For such complex SiPs expensive prototypes cannot be fabricated without a proper design and simulation environment for extensive pre-manufacturing simulations (e.g. for design rule

checks, thermal, electrical). The risk of failing is too high. Thus, a coherent chip-package-board co-design environment needs to be set-up that covers chips and passives, package and the board. SiPoB-3D aims at building up a next level of design methodology for 3D integrated systems, which includes not only the chip and package, but also the board domain.

The consortium will investigate a methodology for mapping the best technology available in companies to design the optimum SiPoB-3D device faster, better and more economic. We must avoid expensive “try and error” loops (time consuming hardware iterations). For design of a compact system, the physics behind the technologies and materials of a compact SiPoB-3D device must be understood. Therefore, emphasize will be put on hardware assessment based on advanced technologies. SiPoB-3D is a holistic approach, which includes investigation and simulation of models that enter into a design library, the design methodology considering multi-physics, and the capabilities setting-up an optimum system as a whole. Data transfer between the different domains needs to be investigated and optimized, especially between the board suppliers and packaged chip suppliers. A global optimum, on chip, package and also on board level needs to be achieved. SiPoB-3D intends to exploit the CoSiP backbone to enable chip/package and board (PCB) co-design for footprints and connectivity. New SiP design rules and checks are a must and will be integrated in the design environment.

A world leading consortium has been set-up. The two European semiconductor suppliers, Infineon Technologies and STMicroelectronics, both with major production in Europe, will collaborate with Continental and Symeo, which both will work on a subsystem on board development, the EDA vendors Atrenta, Docea Power, and CST, and the three small companies Hofmann LP, Schöller-Electronics, and Hitex,

the latter three represent the interface to the board (PCB). These partners are supported by four leading European research institutes. The results of SiPoB-3D will allow shorter time to market and support Europe for managing the complexity and diversity for setting up compact 3D systems as a whole including chip, package, and the board.

Countries: France, Germany

#### Partners:

France	Atrenta, CEA, Docea Power, STMicroelectronics Crolles, STMicroelectronics Grenoble, Université de Savoie
Germany	Continental Automotive, CST, FAU Erlangen-Nuremberg, Fraunhofer IIS/EAS, Hitex Development Tools, Infineon Technologies, Schoeller-Electronics, Symeo, Hofmann Leiterplatten

Expected start date: 01-04-2015

Expected end date: 31-03-2018

### 3.1.7. Project CAT801 TSV-HANDY

#### *TSV HANDY Hvm AND Yield optimisation*

Project leader: Guilhem Delpu (RECIF Technologies)

#### Brief description:

TSV (Through Silicon Via) is a “More-than-Moore” technology that enables new chip architectures. Some challenges reside along the several steps of process to make TSV products cost efficient. The project aims at supporting the HVM ramp-up and improving the yield for manufacturing TSV products.

The project addresses 4 main challenges:

1. The handling of heterogeneous 300mm wafers with edge trim inspection. In fact, on a 3D TSV line, wafers can present highly different mechanical behaviours and physical properties. RECIF targets the development of a 300mm wafer handling platform, which supports as many types of wafer as possible, without having to reconfigure the equipment or swap dedicated modules (like the end effector). This will help end users gaining in equipment flexibility and “up time”, because the current solutions on the market have proven not being stable enough. The resulting platform will allow a usage either as a wafer sorter by end users (like NANIMUM), or as an EFEM for integration by OEM’s (like FOGALE).
2. The development of metrology and new logistical concepts for ultra-thin wafers after they are debonded on 380mm frames The manual handling of cassettes and wafer frames is an important contributor to wafer cracks, and open cassettes will become incompatible with the cleanliness requirement, driven by the shrinking of the pitch for micro-bumps (down to 20µm). There is a need to bring “Front End” methods and best practices, to “Middle End” (TSV lines). But 300mm modules and automation equipment are not compatible to handle 380mm film frames, because of their dimensions. For instance, a 300mm load port cannot handle 380mm substrates due to mechanical interferences. However, a solution is to consider re-using some of the 450mm modules that have been designed already (cf: CATRENE and ENIAC JU 450mm projects), and adapt it to the need of 380mm film frames. This way, industry will take benefit from existing standardized interfaces, with dimensions that are compliant with substrates wider

than 300mm, up to 450mm. ENTEGRIS and RECIF have designed 450mm modules which can be adapted to support the handling of film frames, within a cleaner and highly automated environment. ENTEGRIS 450mm carrier with 380mm insert for frames will be handled by RECIF 450mm handling platform. ENTEGRIS will develop new carriers to be compatible with higher level of automation, and the partners will demonstrate the industrial relevance of tracking the wafers debonded on frames thanks to RF tags integrated into the frame, at substrate level.

3. The investigations for the FO-WLP process, for round wafers larger than 300mm The project will investigate the manufacturing of surfaces larger than 300mm in Fan-Out Wafer Level Packaging for advanced packaging. In fact, since in this process, the size of the reconstituted mold wafer is independent of the original incoming silicon, GaAs or SiGe wafer, processing larger panels drives the cost per die down. Therefore, current 300mm wafer diameter for Fan-Out WLP needs to be enlarged (batch processing of large panel) and 330mm reconstituted wafer for Fan-Out WLP/eWLB and 450mm Si wafer for Fan-In WLP/WLCSP and Fan-Out WLP/eWLB, need to be studied and considered as next steps to be implemented in high volume manufacturing environment.
4. The improvement of temporary bonding and debonding processes. The work on temporary bonding consist in integrating the coating and bonding capability for “novel adhesives solutions” in order to increase the throughput and the performance of the temporary bonding process. On the debonding side, the project will evaluate the debonding process with wafers bonded with this new process and

implement the new standardization rule developed in the project (re-using 450mm automation modules like carriers and handling platform).

Synergies will be created with other CATRENE projects like NGC450, SOI450, MASTER\_3D and with the ENIAC JU EEM450PR project. The industrial partners intend to release new products to the market by early 2018.

Countries: Austria, Belgium, France, Germany, Portugal

#### Partners:

Austria	EV Group E. Thallner
Belgium	Imec
France	CEA-LETI, Fogale Nanotech, RECIF Technologies, STMicroelectronics Crolles
Germany	ENTEGRIS
Portugal	NANIUM

Expected start date: 01-04-2015

Expected end date: 31-03-2018

### 3.1.8. Project CAT802 SAM3

*Smart Analysis Methods for 3D Integration in Advanced Microsystems and Corresponding Materials*

Project leader: Klaus Pressel (Infineon Technologies)

#### Brief description:

More-than-Moore (MtM), System-in-Package (SiP), as well as 3D high-density integration technologies are a prerequisite for enabling the design of compact microelectronic devices and are enablers for European technology leadership. With increasing integration density the impact of right material choices is becoming of outstanding importance (e.g. electrical data, stress, adhesion, CTE matching). During the

last decade all package materials have been changed, which is a consequence of miniaturisation as well as integration of more functionality into smaller volume. We expect that this trend in assembly and packaging will proceed (see discussions in ITRS roadmap, iNEMI roadmap, as well as international conferences). Increased functional density and small foot-print of innovative systems are achieved by innovative interconnects, such as Through Encapsulant Via (TEV), Through Silicon Vias (TSV) and redistribution layers applied to advanced assembly and packaging technologies. Examples of such advanced packaging technologies are chip embedding in mold materials (eWLB), chip embedding in laminate materials as well as 3D stacking.

For these new and complex devices, failure analysis becomes a more and more expensive part of product development. An advanced failure analysis strongly supports to meet the right timing for product introduction, a fact that provides an outstanding saving potential for companies. New materials and processes must be developed and qualified requiring effective analysis techniques to understand new failure modes and reliability limiting factors caused by thermo-mechanical mismatch, residual stresses and interaction of new materials and processes. Thus, for development of complex heterogeneous SiP devices and for reaching required reliability, innovations in failure diagnostic and material analysis are required and must be aligned to the SiP technology developments in effective failure analysis workflows.

In particular, the existing failure analysis techniques are limited in localizing electrical defects in these compact SiP devices with multi-level wiring. Efficient and artefact free sample preparation to apply physical analysis techniques are limited. Techniques to determine local residual stresses and material parameter within the package are required for reliability modelling.

The four major European semiconductor and system suppliers Infineon, STMicroelectronics, Bosch and Thales will collaborate with eleven equipment and analytical method suppliers from Germany and France. The work is supported by five academic institute partners. The SAM3 project will improve the capability of the semiconductor and system suppliers (Infineon, STMicroelectronics, Bosch, and Thales) to avoid defects and failures during product development based on better material understanding. Comprehensive, well adapted and effective failure analysis work flows provide essential support for technology development, process and product qualification, and quality/process control during fabrication. The project results will provide inputs for advanced simulation approaches or reliability models that can be used to identify and consider reliability problems already during the product development phase (“design for reliability”). Such concepts gain increasing importance since they allow to reduce time-to-market and development cost. In addition proper analysis work flows allow reliability assessments to achieve short-time to market readiness, proven application potential, and future customer acceptance of innovative MtM, SiP and 3D integration solutions. Besides, the SAM3 project will allow the equipment suppliers to better understand the needs of the semiconductor and system suppliers and tune their roadmaps according to the need of the industry with worldwide market perspectives.

Countries: France, Germany

#### Partners:

France	CNRS-AMU-LP3, DIGIT CONCEPT, GREMAN (UMR 7347), ORSAY-PHYSICS, STMicroelectronics Tours, STMicroelectronics Rousset, STMicroelectronics
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Germany	3D-Micromac, Fraunhofer Institute for Mechanics of Materials, Infineon Technologies, Muegge, Nanoworld Services, point electronic, PVA TePla Analytical Systems, Reutlingen University, Robert Bosch, SmarAct, WITec
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Expected start date: 01-03-2015

Expected end date: 28-02-2018

## 3.2. Projects ended in 2014

### 3.2.1. Overview Table

Call #	Project Number	Acronym	Work Area
1	CA303	OPTIMISE	Automotive and Transport
2	CA402	THOR	Health and the Ageing Society
3	CA308	ICAF	Automotive and Transport
3	CA403	RELY	Health and the Ageing Society
3	CT206	Reaching22	Semiconductor Process and Integration
3	CT305	SOI450	Equipment, Materials and Manufacturing
3	CT306	NGC450	Equipment, Materials and Manufacturing
3	CT402	9D-Sense	Semiconductor Process and Integration
4	CT210	Dynamic-ULP	Semiconductor Process and Integration

### 3.2.2. Project CA303 OPTIMISE

*Optimisation of Mitigations for Soft, firm and hard Errors*

Project leader: Florent Miller (EADS)

Brief description:

The reliability of electronic components is an essential element for automotive power electronic, avionic and space applications. However, commercially available submicron technologies are inherently sensitive to the incidence of energetic particles due to the low voltages at which they work (3,3, 2,5, 1.8 V...) and due to their very small node size. As example, the high sensitivity of the advanced technologies (below 90nm and down to 28nm) was assessed

experimentally in the project and the associated risk for applications at ground and airplane levels was quantified with a potential increase in the error rate reaching almost +50% on 28nm technologies.

Starting from this statement, OPTIMISE project followed two main goals, applied to three different applications automotive power electronic, avionic-FPGA and space ASICs:

- Acquire knowledge on new radiation threats that may impact future electronic equipment and work in close collaboration with standardization bodies to propose guidelines or standards to be able to perform relevant risk assessment;

- Develop and validate mitigation techniques from layout to application architecture levels.

The first step towards the realisation of these two objectives was the development of tools for the radiation sensitivity assessment. In the following of the PARACHUTE project (MEDEA frame), the relevancy of using laser and emulation platforms to study the radiation sensitivity has been pursued on a wide variety of devices (SRAM, test vehicles, SRAM based FPGA, ...). In addition, the first experiments in the world demonstrating the possibility to simulate destructive failures using laser in Wide Band Gap power devices have been successfully performed by IMS and EADS allowing achieving one of the first detailed study of the radiation induced failures in SiC power devices.

Automotive application

Acquire knowledge

An important highlight is the standardized method proposed by Renault regarding reliability assessment due to radiation effects on power components.

Mitigations development & new products

- CNM designed an IGBT with an internal current sensing. it has been demonstrated the possibility to measure a SEL (Single Event Latchup through the sense electrode, without impact on main circuit, paving the way to possible early detection of destructive event, especially in the case of slow power electronics devices.
- STM Tours has been able to develop a new SiC diode technology and will propose a full range of SiC 1200V diodes in 2014 benefiting of improvements on radiation tolerance.

Avionic application

Acquire knowledge

Airbus proposed inputs for the update of the radiation test standards for avionics.

Mitigations development & new products

An Avionic I/O board implemented in a Stratix IV FPGA has then been tested using a fault injection platform:

- A state of the art DRAM fault-tolerant controller developed and patented by EADS was enhanced to support the more advanced DDR3 memory type used in the system.
- The CPU Checker IP was developed to detect errors enabling a continuous observation of the microprocessor execution without disturbing it.
- A selective mitigation approach developed by TIMA focuses on error detection in the FPGA Look-Up Table (LUT) configurations taking advantage of unused FPGAs resources.

SPACE ASIC

Acquire knowledge

On the standards side RIIF initiative has been launched.

Mitigations development & new products

- UC3M developed the AMUSE tool able to classify the cells of a circuit with respect to Single Event Effects (SEE).
- Arquimea synthesized a SEL free ASIC with a hardened 90nm CMOS library developed during the project by ATMEL. The measures of SETs width have shown an improved SET robustness of the hardened library compared to 90nm commercial cells (ratio around 100). The radiation assessment of

the 8T SRAM cells has been performed by UIB.

- In order to improve the design of robust circuits, iRoC and TIMA developed three innovative Radiation Hardening by Design (RHBD) solutions. These techniques have been used to design three hardened versions of the LEON2 processor synthesized using the ATMEL's hardened library. These hardening techniques have been assessed by performing fault injection simulations and have been validated by iRoC and TIMA. Finally, these hardening techniques have been completed by the CPU checker proposed by UC3M in the avionic chain value and ported by UC3M and iRoC into the three hardened LEON2 design. These mitigation techniques were implemented in the test vehicle V53, which was manufactured at the end of May 2014 and tested under heavy ion in June 2014. The SEE results of the LEON2 circuits have shown a very good SET coverage protection with a benefit on the silicon area, and power overhead, without degrading the performances. On the exploitation side, this hardened library is used to develop a new ATMEL space-qualified SPARC processor that will address the space market.

Countries: France, Spain

**Partners:**

France	Airbus Defense and Space, ATMEL NANTES, CEA, Continental Automotive, EADS Innovation Works, IMS Lab, iRoC Technologies, RENAULT, STMicroelectronics, TIMA, Universite Provence IM2NP, Valeo Interior Controls
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Spain	Alter Technology Group, Arquimea Ingenieria, CNM-Centro Nacional de Microelec- tronica IMB, D&T Microelectronica, Thales Alenia Space, UIB-University of Balearic Islands, Universidad Carlos III Madrid
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Start date: 01-01-2015

End date: 31-12-2017

**3.2.3. Project CA402 THOR**

*Striking technologies for Power*

Project leader: Mark van Helvoort (Philips Healthcare)

**Brief description:**

The THOR Project, coordinated by Philips Healthcare, has delivered solutions for packaging, cooling and electromagnetic compatibility. This helps industry to transform the Silicon Carbide (SiC) market from a device to a power modules business. This transformation will lead to a jump in growth of the SiC device market from 26% to 39% within the next year according to Yole Development.

In modern power converters, most of the volume is occupied by cooling components and electrical filters. SiC based power devices reduce both the requirements on cooling and filtering. THOR has exploited this aspect by developing high temperature packaging, compact cooling systems and smaller filters. Compact power conversion systems with a very high power density have been demonstrated in three application areas: aeronautics, automotive and healthcare.

These compact and highly efficient converters are essential for addressing the environmental challenges in terms of CO<sub>2</sub> emission and over reliance on fossil fuels. Power converters will significantly reduce the weight of cabling in a single aircraft thus diminishing fuel consump-

tion with an additional 30% being saved by storing transient energy during braking. In the medical area, more compact systems at a lower cost helps to address the health challenges in the ageing society.

Key to the success of the THOR project was its coverage of the full supply chain from semiconductor device level to power system integrator in combination with three application areas to leverage the economy of scale. The commercial advantage is a stronger competitive situation for the different industrial partners, because recent advancements in power electronics technology provided by the academic partners have been integrated into advanced applications. This ranges from SiC and Sol technology to full compact power converters integrated in large systems.

Such broad coverage was made possible by the unique support of two large European support programmes: CATRENE and EURIPIDES<sup>2</sup>. The information sharing and cross-fertilization within the THOR consortium was excellent; more than 70 reports with results have been internally exchanged and new, long-lasting, collaborations have been established. Furthermore, the key players within THOR guaranteed efficient cooperation with other related European projects.

THOR also shared its newly generated knowledge amongst the academic and industrial public. More than 30 papers have been written, 25 presentations were given and 12 patent applications have been submitted. A book on EMC of large systems and installations has also been published in Dutch and is currently being translated.

The first products based on THOR technology are already available on the market. In September 2012, STMicroelectronics released their SiC diodes for photovoltaic converters. They will extend their range this year to ad-

ditional applications and SiC Mosfets will follow soon. Soitec and NXP have a new silicon-on-insulator process in place facilitating the design of high temperature drivers and the integration of low-voltage and high-voltage integration at lower cost.

For electric vehicles, Valeo has demonstrated a compact air-cooled high-voltage DC/DC-converter with efficiency 93% and 95% over a very broad output power range. The vapour chamber and heat sink have been designed such that the cooling capabilities of the converter are independent of the mounting orientation, thus offering large flexibility to car designers.

Labinal Power Systems, Airbus Group Innovations, Thales Microelectronics and CIRTEM have demonstrated a compact power converter, which covers a very large temperature range such that it can be located at both aeronautic engines and in brakes on airplanes (very high temperatures).

Philips Healthcare and the Dutch SME Prodrive demonstrated the capabilities of full digital control for power electronics. Among others, a compact high voltage power supply was shown with an ideal topology for introducing SiC components. Pilot tests in hospitals are already ongoing. Further, a feedback system was developed, which can correct up to 10 dB variations in amplifier gain.

Countries: Belgium, France, The Netherlands

**Partners:**

Belgium	NXP Semiconductors
France	Airbus Group Innovations, Ampère Insa Lyon, Cirtem, Epsilon Ingénierie, Labinal Power Systems (Safran), Soitec, ST Microelectronics, Thales Microelectronics, University de Versailles-Saint-Quentin-en-Yvelines, Valeo Systèmes de Contrôles Moteur

The Netherlands	Bruco Integrated Circuits, NXP Semiconductors, Philips Healthcare, Prodrive, TUE-Technical University Eindhoven
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Start date: 01-10-2010  
End date: 31-03-2014

### 3.2.4. Project CA308 ICAF

#### Image Capture of the Future

Project leader: Jochem Herrmann (Adimec)

#### Brief description:

ICAF project developed and researched hardware and processing algorithms for single lens 3D camera systems, multi view camera systems, broadcast video over internet protocol systems and high speed vision cameras for 3D applications. The project delivered 3D single lens microstereopsis camera, multi view systems, depth from luminance, depth image based rendering, super resolution of depth maps and denoising and demosaicing for super slow motion HD cameras (including IP based transmission). In particular the project delivered the first 3D single lens stereopsis camera and the first HDTV slow motion camera beyond triple speed that can continuously output a slow motion stream together with a normal HDTV stream. In addition the project provided high data rate transmission ICs to extend the worldwide CoaXPress standard with new protocols and higher bit rates up to 12.5 Gbps.

The products that incorporate results of the ICAF project are professional broadcast cameras, cameras for machine vision, the global security and medical markets, CoaXPress transmission ICs, CMOS image sensors and compression IP. These products are manufactured within Europe and shipped worldwide. The exploitation results and expected market impact by partners are:

- Adimec has the first commercial camera with 2 Gpix/s continuous data rate streaming capability and the first rugged surveillance camera with CoaXPress;
- Axon has won 5 awards with his implementation and definition of the new Video over IP standards SMPTE2022 and AVB;
- EqcoLogic introduced its next-gen CoaXPress transceiver solutions. First engineering samples have been sent to selected customers for evaluation;
- Grass Valley has introduced a very successful 6x slow motion HDTV camera. They won 3 awards with this camera;
- Grass Valley has patented the principle used in the single lens microstereopsis camera;
- IntoPix has strengthened its position in video compression with first J2K Video over IP reference FPGA design;
- On-Semi has Strengthening its position in state of the art high speed and industrial imaging;
- TU Delft developed a novel method for automatic transformation of 2D images into 3D and has applied for patents in Europe, US, Japan, and Korea. It spawned a spin-off company to exploit the IP;
- University of Ghent has developed new denoising, demosaicing and super-resolution techniques for time-of-flight, microstereopsis and regular broadcast cameras;
- Hasselt University has developed novel high-quality and real-time camera interpolation.

A pro-active behaviour of all partners resulted in a smooth project management with minimal delays in deliverables and a high number of quality results compared to the size of the project.

Countries: Belgium, The Netherlands

#### Partners:

Belgium	EqcoLogic, Hasselt University, intoPIX -secure image technology, ON Semiconductor, University of Ghent
The Netherlands	Adimec, AXON, Grass Valley, TUD-Technical University Delft

Start date: 01-10-2011  
End date: 30-09-2014

### 3.2.5. Project CA403 RELY

#### Design for RELIABILITY of SoCs for Applications like Transportation, Medical, and Industrial Automation

Project leader: Georg Georgakos (Infineon Technologies)

#### Brief description:

One of the main problems in ICs down-scaling is the high susceptibility to smallest interferences and deviations. Nevertheless, safety critical integrated systems inside cars, planes, medical implants, etc. have to be reliable despite an increasing ageing and failure sensitivity. Today, this reliability is achieved by extremely expensive means like guard bending or redundancy. Starting from this statement, RELY targeted two main goals: ensure system reliability along the entire value chain, and enable new SoCs with a new level of functionality through increased reliability at reasonable costs. These two general goals can be broken down into three technical areas:

1. Prediction of reliability at all phases of the system design.
2. Solutions to increase the system reliability.

3. Reduction of the area and cost overhead for the reliability measures through optimization.

#### Early and fast reliability prediction

At the transistor, gate, and RT level, ageing effects are already modelled thanks to earlier projects such as HONEY or OPTIMISE. The main challenges for RELY were: increasing modelling speed, improving model accuracy, increasing the abstraction level, and including additional effects.

As regard to model accuracy, the RELY research has provided models for the Negative Bias Temperature Instability (NBTI), the Hot Carrier Degradation (HCD), the Time Dependent Dielectric Breakdown (TDDB), the soft breakdown (SDB) and the electro-migration.

At levels of abstraction above RT level, CEA LIST integrated a reliability-aware system level simulation methodology into their SESAME tool which is 15 times faster compared to gate level. A simulation speed improvement of four orders of magnitude against SPICE has been observed using a phase space based approach developed by OFFIS as subcontractor from Infineon.

Finally, ITEM developed a new methodology enabling the selection of optimal design parameters (in terms of functionality as well as reliability) for analogue circuits, demonstrating two orders of magnitude speed-up against SPICE. Last but not least, Fraunhofer developed a methodology to generate degradation models for all available tool interfaces directly from the characterization data enabling usage of the commercially available tools.

#### Solutions to increase the system reliability at optimized costs

Using these prediction methodologies, several run-time reliability management strategies were developed, such as sensor redundancy

schemes (AIRBUS), in-situ degradation sensing (TUM LTE), sensor output data aggregation and reliability management utilizing a dedicated reliability layer (TUM LIS), or selective hardening (ITTP). X-FAB presented a highly reliable high-temperature technology with improved electro-migration resistance. The partners Infineon, X-FAB and MunEDA developed techniques to prevent fatal field returns due to early detection before tape-out. Finally, a new methodology based on product like circuitries for a hundred times faster detection of quality problems in the fab, was developed by Infineon.

The project consortium finally presented several demonstrators, successfully using these design techniques at several levels: One of the major demonstrators, to be developed in a 40nm Infineon technology was not ready at project end, but will nevertheless be presented later by Infineon and TUM at their own cost. This test chip will test the applicability of the RELY methodologies in an automotive context, analysing the effectiveness of critical path detection and adaptation, as developed by TUM. ITEM presented a test chip from the medical devices area; a mixed signal neural interface. The power overhead, stemming from the overdesign of the reference circuit could be reduced by 20% in the analogue and 37% in the digital part under the same reliability target. AIRBUS and Fraunhofer jointly developed a redundant, thus highly reliable sensor array for avionic applications in extremely harsh environments. This demonstrator presented how to build reliable systems from unreliable components, especially sensors.

Countries: France, Germany, The Netherlands, Romania

#### Partners:

France	ATMEL NANTES, CEA-List, EADS Innovation Works, ENST, STMicroelectronics
Germany	EADS Innovation Works, Fraunhofer-IISB, Infineon Technologies, MunEDA, TUM - Technical University Munich, UHB - University of Bremen, X-FAB Semiconductor Foundries
The Netherlands	Intrinsic-ID
Romania	Infineon Technologies

Start date: 01-05-2011  
End date: 31-07-2014

#### 3.2.6. Project CT208 Reaching22

*REsearch on optimal ArCHitecture and INteGration of 22/20nm node core digital CMOS technology- Electrical proof of concept*

Project leader: Gilles Thomas  
(STMicroelectronics)

#### Brief description:

The project REACHING22 was labelled in 2010 and started on 01 April 2011. The works, done in the initial phase of REACHING22, related to 28nm FDSOI transistor architecture qualification for next generation of application processor was a complete success and the activity completed according to plan. A complex SoC demonstrator of 69mm<sup>2</sup> was designed by ST-Ericsson. With a 100% tool set compatibility with 28nm bulk the FDSOI 28nm offers a 40% frequency boost at nominal V<sub>dd</sub> of 1V, 100mV reduced V<sub>min</sub> on SRAM and 40% less variability on NMOS. These encouraging results led to consider FDSOI transistor architecture as the major technology option for the 20nm node, displacing the 20nm bulk which was concurrently developed and could not show a comparable

power/performance compromise.

In a second phase, the project REACHING22 chose to develop the 20nm FDSOI transistor architecture (at module level in WP3) and towards a full integration in WP4 for the ST Crolles fab. Gate length more aggressively sized than 20nm were evaluated while the multilevel interconnect scheme could retain metal pitches defined for the 20nm bulk giving rise to an intermediate technology node with mixed critical dimension dubbed "14nmFDSOI". The technology has been renamed "14FDSOI" because device performances compare to "16-14nm" node specs. In Q3 2013, ST-Ericsson left the consortium. An initial simple test chip (C20FIRST) was designed and the initial integration flow permitted the fabrication of a first lot. Although functional, this initial silicon was way off the predefined target. In the final 3 quarters of the project a big effort was made by CEA-LETI and ST to improve the process flow and boost the performance. A more complex mask set was designed to initiate the development of the 14FDSOI technology platform and to develop the complex Middle Of the Line (MoL) section of the process requiring multiple double patterning steps. At the end of the project process improvements made during the project are bringing DC parameters within 90-95% (for NMOS) and within 70% (for PMOS) of the target. AC parameters measured on ring oscillators are reaching 78-80% of the predefined performance which is a good achievement at this early stage of the technology development. To improve, further investment is needed and planned. The change from node 20 performance specs to node 14 specs made it very difficult to achieve speed goal at Ring Oscillator level; the project studied all options to boost performance including the gate last approach, as well as major process improvement in the critical MoL to reduce parasitic capacitances and resistances which will ensure 100% of AC and DC characteristics to be achieved.

Countries: Belgium, France

#### Partners:

Belgium	UCL-Catholic University of Louvain
France	CEA-Leti, IMEP/INPG, LTM/CNRS, Soitec, ST-Ericsson, STMicroelectronics

Start date: 01-04-2011  
End date: 31-03-2014

#### 3.2.7. Project CT305 SOI450

*Development of 450mm SOI substrates, related technologies and equipment*

Project leader: Francois Brunier (Soitec)

#### Brief description:

The SOI450 project started in November 2011 and finished in June 2014, enabling to reach an unprecedented maturity level on SOI process and related technologies and equipment in 450mm. More over Resolving 450mm barriers with our consortium brought innovating solutions in 300mm "Fully depleted" SOI processes and allow for retrofitting in the 300mm framework. In particular the cleaning solutions developed on EVG bonding tool using Megasonic and the introduction of the Adixen APA in the SOITEC 300mm FDSOI substrate line improve the yield and optimize the FOUP cleaning cost.

The main achievements in the project are the following:

- Soitec demonstrated the feasibility of the Smart Cut™ process, evaluating each step of SOI substrate process flow in 450mm and measuring the existing gaps with targeted objectives. Most process steps reached a good maturity level, the main technical roadblock at his stage being the quality of

H implantation.

- Adixen, brought the study and assembly of the APA450 prototype, and its installation at G450C (Albany, USA), Adixen takes a forefront position in the area of molecular contamination, and especially toward international customers.
- EVG demonstrated successful fully automated wafer bonding on 450mm substrates for SOI manufacturing with fusion bonding process.
- Altatech developed a top table 450mm Altasight metrology system and interface with major players in material and process developments.
- INTEL; last but not least, thanks to the intermediate of INTEL a collaboration path with G450C was opened.

Thanks to the SOI450 program, the members of this consortium are ideally positioned when a recovery of 450mm activity and roadmap will occur.

Countries: Austria, Belgium, France, Germany, Ireland, The Netherlands

#### Partners:

Austria	EV Group E. Thallner
Belgium	Imec
France	Adixen Vacuum Products, Altatech, CEA-LETI, Soitec
Germany	Mattson
Ireland	Intel
The Netherlands	ASM Europe

Start date: 01-11-2011

End date: 30-06-2014

#### 3.2.8. Project CT306 NGC450

Project leader: Guilhem Delpu (RECIF Technologies)

Brief description:

NGC450 project aimed to enable in Europe the development of a wafer handling platform, dedicated to support the 450mm wafer size migration. Considering the ever evolving 450mm global environment during the project time line, this concrete goal was a real challenge to achieve. The excellent collaboration and the efficient management within the project helped to complete the targets within the planned timing and to end with a successful project, successful in the innovation point of view but also in the industrial exploitation perspectives.

Technical progress, innovations

The projects brought innovation in the following sub-equipment:

- Atmospheric robotics: The challenge was to transfer heavier substrates through a longer distance within an equal period of time, despite increased vibrations phenomenon and more challenging mechanical properties of the substrate. The atmospheric robotics developed during the project is able to maintain the same throughput than a 300mm system, with an optimal wafer safety and extreme cleanliness.
- Vacuum robotics: Asys partner proved the possibility to produce an easily scalable vacuum chamber, maintaining the same throughput than a 300mm cluster system.
- Mini environment: Compliance with 16-22nm cleanliness and airborne molecular contamination has been proven 16-22 nm compatible (and beyond).
- Atmospheric and vacuum compliant End effectors: The challenge was to develop

Vibration free, stiff and very thin End effectors despite more challenging dimensions. Besides the End effector had to be compliant with low defectivity and contamination challenges (particle and metallic). The end effectors developed in the project have proven their efficiency with safe handling at Imec and low defectivity (cf CEA-LETI assessment).

- Software interface: AIS has proven the efficiency and stability of their software able to drive a multi-equipment cluster with a high performance interface.
- Advanced metal contamination characterization: The project has allowed specific VPD and LPD set-ups implementation on 450mm wafer and optimized metallic contaminants collection coupled to the advanced ICPMS characterizations. The set-ups efficiency and sensitivity has been proved by CEA-LETI.

Industrial exploitation and benefit per partner company

At this precise moment, the 450mm market outlook is unclear and it is thus very difficult to “predict” when the first 450mm order will come from industry. However, in this 450mm ramp-up perspective, the NGC450 project developed state-of-the art “off the shelf solutions” for any process or metrology supplier. Besides, the NGC450 partners will be among the first to be activated thanks to their network and because they are at the beginning of the value chain and the consortium partners can very quickly and easily supply the developed solutions; because they led the development till the end.

The absence of immediate payback doesn't make a commercial failure of this project. What are the benefits that can be used outside from a pure 450mm perspective?

- AIS will capitalize on their developments involving web services to enrich their current product offer for semiconductor business, but also railways technology, factory automation, photovoltaic, optical industry, pharmaceutical, general automation solutions. Now that AIS controller and RECIF 450mm EFEM are integrated, the path will be very easy to perform an integration on a RECIF 300mm system.
- Asys and HAP are into 300mm business thanks to the NGC450 project, to supply a big European OEM. This achievement led to further businesses in Asia, thanks to presentation to SEMATECH consortia. HAP gained experience and visibility for their end-effector business, which can be valued beyond 450mm arena.
- CEA-LETI has demonstrated their leading edge capabilities to develop advanced set-ups for chemical collection and assessment of metal contamination. They will participate to the “2015 International Conference on Frontiers of Characterization and Metrology for Nanoelectronics”.
- EVG has been presenting the developed SOI bonding system at several exhibitions (presentations at Semicon EU) and has been advertising this product to existing and potential customers through its global sales and customer support organization. The EVG systems are candidates to receive some of the atmospheric robotics modules developed within NGC450.
- HAP gained experience and visibility for their end-effector business, which can be valued beyond 450mm arena.
- RECIF gained a lot of visibility thanks to this project and has set-up strong links with G450C. Several OEM's are expecting from RECIF to supply 300mm EFEM solutions, based on the successful demonstration of

NGC450 platform. RECIF has also improved its 300mm offer thanks to NGC450 learning, mainly on the cleanliness point of view. The company could achieve breakthrough results on its 300mm platform, when assessing the particle adders per wafer pass (PWP) on a KLA SP3, down to 26nm and 40nm particle size. RECIF sees a strong opportunity to disseminate and re-use some of the 450mm designs, for 300mm direct applications related to the handling of ultra-thin wafers (around 50µ thickness), after they are de-bonded on film frames (“More-than-Moore” applications). Manufacturing methods are mainly coming from the world of “back end” (BEOL). These methods will not be “clean enough” and will not offer sufficient automation levels to allow the manufacturing in high volume, with an acceptable yield.

The manual handling of cassettes and wafer frames is an important contributor to wafer cracks, and open cassettes will become incompatible with the cleanliness requirement, driven by the shrinking of the pitch for micro-bumps (down to 20µm).

There is a need to bring “Front End” methods and best practices, to “Middle End”(TSV lines).

But 300mm modules and automation equipment are not compatible to handle 380mm film frames, because of their dimensions. For instance, a 300mm load port can’t handle 380mm substrates due to mechanical interferences.

However, a solution is to consider re-using some of the 450mm modules that have been designed already, and adapt it to the need of 380mm film frames. This way, industry will take benefit from existing standardized interfaces, with dimensions that are compliant with substrates wider than 300mm, up to 450mm.

Countries: Austria, Germany, France, Ireland

**Partners:**

Austria	EV Group E. Thallner
France	CEA-LETI, RECIF Technologies
Germany	AIS Automation Dresden, ASYS, Fraunhofer – IISB, HAP
Ireland	Intel

Start date: 01-11-2011

End date: 31-12-2014

**3.2.9. Project CT402 9D-Sense**

*Autonomous Nine Degrees of Freedom Sensor Module*

Project leader: Ricardo Zamora (Robert Bosch)

**Brief description:**

The main goal of 9D-Sense was to provide technologies and methods to enable a stand-alone 9D sensor chip integrating a 3-axis accelerometer, a 3-axis gyroscope and a 3-axis magnetometer on silicon wafer based technology. The projects lead to several innovations summarised below:

1. Sensing module

One major goal for the Bosch MEMS department was to reduce the package size of multi degree of freedom sensor units. 9D-Sense delivered a 5x5x1 mm<sup>3</sup> package compare to 10x8x3.8 state of the art solution where only one axis accelerometers and gyroscope were included in a single chip and the integration of three different sensors was only available at package level. This greatly helps to reduce size and cost of sensor production. Furthermore, this concept has the advantage of an inherent precise adjustment of all space axis of each sensor to each other which improves measurement accuracy. This global innovation was possible thanks to:

- An innovative MEMS-based Lorentz force magnetometers developed by FhG-ISIT.
- Redistribution Layer, Through Silicon Via and Fine Pitch Bumping allowing savings in die area of up to 25%.
- Innovation in Readout electronics with an innovative delta sigma ADC Gyroscope-ASIC and a Lorentz Force Magnetometer Excitation and Readout.

2. Thin film Battery

Realization of full 3D-batteries on structured substrates with CVD and/or ALD layers.

3. Energy Harvesters

- Kinetic Harvester (HSG-IMIT) using the heel-strike during walking has been realised. The achieved power output is sufficient to operate a fully energy autonomous mobile sensor system.
- Thermoelectric Generator (TEG) (Micropelt) a novel chemical etch process using Methane was developed.

4. Sensor Fusion

- Algorithms (Bosch Sensortec): improvement of pedestrian tracking algorithms using inertial and magnetic sensors only.
- Sensor fusion for indoor navigation (HSG-IMIT): relying on step detection [1] and Kalman filtering [2,3,4] had been investigated.
- Sensor fusion for gesture recognition (HSG-IMIT): Based on the concept of dynamic time warping an inertial sensor-based gesture recognition algorithm was developed.

5. Applications

- Smart Wristlet: The innovations in several ways: It is designed to be integrated into a wide Internet of Things ecosystem; The

integrated protocols are designed to be very battery friendly, Built-in security and Ergonomics.

- Orthosis (OttoBock HealthCare): E-Mag Active orthoses was modified and is now controlled by a 9D-Sense module allowing improvements in the learning mode of the orthoses.

Countries: Austria, Finland, France, Germany

**Partners:**

Austria	Austria Microsystems
Finland	University of Helsinki
France	Gemalto
Germany	Fraunhofer, HSG-IMIT, Micropelt, Otto Bock Healthcare, Bosch Sensortec, Robert Bosch, Technische Universität Darmstadt

Start date: 01-11-2011

End date: 31-10-2014

**3.2.10. Project CT210 Dynamic-ULP**

*High DYNAMIC range multiprocessor for Ultra Low Power mobile devices*

Project leader: Philippe Garcin (STMicroelectronics)

**Brief description:**

The common goal of ST, ST-Ericsson, CEA and their partners has been to get an efficient design platform for use by European designers preparing the next devices in the Mobile Wireless and Consumer Appliances where access to the multimedia contents will have no latency to the user.

For this purpose, DYNAMIC-ULP has developed advanced process modules and contribute to two successive generations of design platforms

(design kit, models, libraries) based on CMOS FDSOI technologies (Fully Depleted Silicon on Insulator) for European manufacturing facilities.

The success of DYNAMIC-ULP was achieved on 2 complete process nodes:

- A 28nm FDSOI design platform: the project allowed this platform to reach full maturity. Platform efficiency has been demonstrated on a high complexity System-on-Chip, till silicon level. The project was 80% design oriented, thus acting as a key link between developments on transistor architectures (inherited from REACHING22) and future manufacturing aspects performed by the Places2Be pilot line project. Actions towards new FDSOI-oriented methodologies included methods for SRAM development and design specific logic IP block. Feasibility studies to integrate forward and back biasing and DVFS techniques are being encompassed into a test chip connecting all relevant IP block into a front-end receiver design for 4G application. All the IPs were validated on ST-Crolles silicon run opening the volume production on the process node.
- A 14nm FDSOI design platform: the project has evolved towards this platform up to technology qualification. Process modules have been developed by an extensive usage of PROMO and QLIB test chips in order to assess the performance of the technology. A new tool for standard cell verification provided a speed improvement of a factor 8 compared to Monte Carlo method. The same hybrid solution has been ported to 14nm thus enabling the co-integration of bulk and SOI devices on the same die.

The FDSOI process is keeping the simplicity of the planar technology used for design since the Integrated Circuit has been manufactured. This legacy is guarantying a high reliability as

well as a low manufacturing cost. The second advantage clearly demonstrated is the time to market: most of previously circuit designed for bulk can be transferred into ta FDSOI database thanks to the methodology demonstrated by Dynamic-ULP deliverables.

The penetration of the FDSOI is just at the early stages where the ULP (Ultra Low Power) are a mandatory requirement for all mobile devices, all IoT (Internet of Thing) where the autonomy is the main differentiator on the market. ECSEL projects (Thing2Do) and (Way s2goFast) will be entrusted with the exploitation of these superior process nodes into a large variety of consumer market segments.

Countries: France, Sweden, Turkey

Partners:

France	Atrenta, CEA, CEA-LETI, Dolphin Integration, Infinscale, Soitec, ST-Ericsson, STMicroelectronics, STMicroelectronics Grenoble
Sweden	Acreo, Lund Institute of Technology, ST-Ericsson
Turkey	Ericsson Mikroelektronik

Start date: 01-01-2012

End date: 31-12-2014



# Appendix A

## CATRENE

### Projects Focus Matrix

### Appendix A. CATRENE Projects Focus Matrix

The CATRENE Projects Focus Matrix identifies the work areas addressed by each project. A maximum of 5 \*s can be allocated to a single project. A \* indicates that the project addresses the work area in question, with this focus growing with each additional \*.

PROJECT NAME	Communication & Digital Lifestyle	Safety & Security	Automotive & Transport	Health and the Ageing Society	Energy Efficiency	Design Technologies	Semiconductor Process & Integration	Equipment, Materials & Manufacturing
CA101 PANAMA	**				*			
CA103 HERTZ	**				*			
CA104 COBRA	***					*		
CA109 SHARP	*			*		***		
CA110 APPSGATE	**			*	*			
CA111 UltraHD-4U	***							
CA112 HARP	**		*		*	*		
CA114 WiCon	***						**	
CA116 CORTIF	***							
CA118 FITNESS	***					**		
CA202 eGo	*	***						
CA206 NewP@ss		***						
CA208 MobiTrust		***						
CA301 HiDRaLoN	*		*	*				
CA303 OPTIMISE			**		*	**		
CA308 ICAF	***	**						

PROJECT NAME	Communication & Digital Lifestyle	Safety & Security	Automotive & Transport	Health and the Ageing Society	Energy Efficiency	Design Technologies	Semiconductor Process & Integration	Equipment, Materials & Manufacturing
CA310 EM4EM			***			**		
CA402 THOR			*	*	*	*		
CA403 RELY			*	*		***		
CA501 COMCAS	**				**	*		
CA502 SEEL			**		***			
CA505 BENEFIC	*				**	**		
CA507 GREETINGS16					***	**		
CA701 H-INCEPTION						***		
CA703 OpenES	*		*			***		
CT105 3DIM3	*					**	*	
CT204 PASTEUR				*			***	
CT205 REFINED						*	***	
CT206 UTTERMOST						*	***	
CT207 COCOA						*	**	*
CT208 REACHING 22						**	**	
CT209 RF2T4Z SISOC	*					*	***	
CT210 DYNAMIC-ULP	*					**	*	
CT213 3DFF				*	*	*	**	
CT217 RESIST			**			***		
CT218 E450LMDAP								***

PROJECT NAME	Communication & Digital Lifestyle	Safety & Security	Automotive & Transport	Health and the Ageing Society	Energy Efficiency	Design Technologies	Semiconductor Process & Integration	Equipment, Materials & Manufacturing
CT301 EXEPT								***
CT302 TOETS								***
CT305 SOI 450								***
CT306 NGC 450								***
CT312 MASTER_3D								***
CT315 EmPower			*		**		*	
CT402 9D-Sense		*		*		*	**	
CAT120 CISTERN	**	*						
CAT121 EAST	**				*		*	
CAT209 H2O	*	**			*			
CAT406 NEMADE				***			*	
CAT601 SiPoB-3D						***	*	
CAT801 TSV-HANDY							*	***
CAT802 SAM3							*	***



# Appendix B

## Glossary of Terms

Abbreviation	Description
AENEAS	Association for European Nanoelectronics Activities
ALD	Atomic Layer Deposition
AMC	Academic Medical Center
ASICs	Application Specific Integrated Circuit
BCC	Body Communication Coupling
BEOL	Back End of the Line
BOM	Bill of Materials
CATRENE	Cluster for Application and Technology Research in Europe on Nanoelectronics
CMOS	Complementary Metal Oxide Semiconductor
CVD	Chemical Vapor Deposition
CVP	Controller of Variability and Power
DRAM	Dynamic random-access memory
DTC	Design Technology Conference
ECSEL JU	Electronic Component and Systems for European Leadership Joint Undertaking
EDA	Electronic Design Automation
EFEM	Equipment Front End Module
EMC	Electro Magnetic Coupling
EMI	Electro Magnetic Interface
FDSOI	Fully Depleted Silicon on Insulator
FEM	Front End Module
FOUP	Front Opening Unified Pod

Abbreviation	Description
FP	Full Proposal
FP7	Seventh Framework Programme
FPGA	Field Programmable Gate Array
GaAs	Gallium Arsenide
GaN	Gallium Nitride
Gbit	Gigabit
Gbps	Gigabit per second
GFLOPS	Giga Floating-point Operations Per Second
HCD	Hot Carrier Degradation
HID	High-Intensity Discharge
HK/MG	High-K/Metal Gate
HPC	High Performance Computing
HVM	High volume manufacturing
HW	Hard Ware
I/O	Input/Output
IC	Integrated Circuit
ICPMS	Inductively coupled plasma mass spectrometry
IDM	Integrated Device Manufacturer
IGBT	Insulated Gate Bipolar Transistor
IoT	Internet of Things
ISDA	International Semiconductor Development Alliance
LDMOS	Laterally diffused metal oxide semiconductor

Abbreviation	Description
LP	Low Power
LPD	Liquid Phase Decomposition
LTE	Long-Term Evolution
LUT	Look-Up Table
MASP	Multi-Annual Strategic Plan
MEMS	Micro-Electro-Mechanical Systems
MIMO	Multiple input, Multiple output
MoL	Middle of the Line
MOOC	Massive On-Line Open Courses
NBTI	Negative Bias Temperature Instability
NFC	Near Field Communication
nm	nanometer
NMOS	N-Channel Mosfet
NVM	Non-Volatile Memory
OEM	Original Equipment Manufacturer
PCB	Printed Circuit Board
PMOS	P-Channel Mosfet
PMR	Professional Mobile Radio
PO	Project Outline
PWP	Per wafer pass
PY	Person Year
QoE	Quality of Experience

Abbreviation	Description
QoS	Quality of Service
RDL	Redistribution Layers
RHBD	Radiation Hardening by design
R&D&I	Research, Development and Innovation
RF	Radio Frequency
RFF	Radio Related Functions
RFMEMS	Radio Frequency Micro-electro-mechanical systems
RTL	Register Transfer Level
RTLS	Real-Time Locating System
SDB	Soft breakdown
SDK	Software Development Kit
SEE	Single Event Effects
SEL	Single Event Latchup
Si	Silicon
SiC	Silicon Carbide
SiGe	Silicon Germanium
SiP	Systems in Package
SoC	System on a Chip
SOI	Silicon on Insulator
SRAM	Static random-access Memory
SSL	Solid State Lighting
SST	Silicon Storage Technology

Abbreviation	Description
STB	Set-top box
SW	Soft Ware
TCO	Total Cost of Ownership
TDDB	Time Dependent Dielectric Breakdown
TEV	Through encapsulant via
TLM	Transaction Level Modelling
TSV	Through-Silicon-Via
USB	Universal Storage Bus
UWB	Ultra Wide Band
VMS	Vision Mission Strategy
VPD	Vapor Phase Decomposition
WiFi	Wireless Fidelity
WLB	Wafer level ball grid array
WLCSP	Wafer level chip scale package
WLP	Wafer level packaging
WP	Work Package







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